

In re A	application of:)	
	Kei HAYASAKI et al.)	Group Art Unit: 1756
Application No. 10/624,593)	Examiner: Duda, Kathleen
Filed:	July 23, 2003)	Confirmation No. 7500
For:	METHOD FOR FORMING A PATTERN AND SUBSTRATE- PROCESSING APPARATUS))	
Comm	Stop RCE hissioner for Patents hox 1450		

Alexandria, VA 22313-1450 Sir:

AMENDMENT

In reply to the Final Office Action mailed June 1, 2007, the period for response extending through November 1, 2007, by the concurrently filed Petition for Extension of Time and fee payment, and concurrent with the Request for Continued Examination (RCE) filed herewith, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks begin on page 28 of this paper.